Applicant:

Mark A. Ealey

For:

TRANSVERSE ELECTRODISPLACIVE ACTUATOR ARRAY

1 1. A transverse electrodisplacive actuator array for controlling the optical 2 phasing of a reflective surface comprising: 3 a support structure; 4 a plurality of ferroic electrodisplacive actuator elements extending 5 from a proximate end at said support structure to a distal end; each actuator element 6 including at least one addressable electrode and one common electrode spaced from said 7 addressable electrode and extending along the direction of said proximate and distal ends 8 along the transverse d₃₁ strain axis; 9 a reflective member having a reflective surface and a mounting surface 10 mounted on said actuator elements; and 11 a plurality of addressable contacts and at least one common contact for 12 applying voltage to said addressable and common electrodes to induce a transverse strain 13 in addressed actuator elements to effect an optical phase change in the reflective surface 14 at the addressed actuator elements. 1 2. The transverse electrodisplacive actuator array of claim 1 in which said 2 support structure and said actuator elements are integral.

3. The transverse electrodisplacive actuator array of claim 1 in which said actuator elements are electrostrictive.

1

2

4. The transverse electrodisplacive actuator array of claim 1 in which said 1 2 actuator elements are magnetostrictive. 1 5. The transverse electrodisplacive actuator array of claim 1 in which said 2 actuator elements are piezoelectric. 6. 1 The transverse electrodisplacive actuator array of claim 1 in which said 2 actuator elements are lead magnesium niobate. 1 7. The transverse electrodisplacive actuator array of claim 1 in which said 2 addressable contacts are on a surface of said support structure. 1 8. The transverse electrodisplacive actuator array of claim 7 in which said 2 addressable electrodes extend through said support structures to said addressable 3 contacts. 9. 1 The transverse electrodisplacive actuator array of claim 1 in which said 2 common contact is on a surface of said support structure. 1 10. The transverse electrodisplacive actuator array of claim 9 in which said 2 common electrodes extend through said support structure to said common contact on said

support structure.

3

1 11. The transverse electrodisplacive actuator array of claim 1 in which said common contact is on the said reflective member. 2 12. 1 The transverse electrodisplacive actuator array of claim 11 in which said 2 common electrodes extend through said actuator elements to said common contact on said reflective member. 3 1 13. The transverse electrodisplacive actuator array of claim 1 in which said 2 actuator elements are a ferroelectric material. The transverse electrodisplacive actuator array of claim 1 in which said 1 14. 2 actuator elements are a ferromagnetic material. 1 15. The transverse electrodisplacive actuator array of claim 1 in which said actuator elements are a lead zirconate titanate. 2 1 16. The transverse electrodisplacive actuator array of claim 1 in which said 2 actuator elements are a ferroic ceramic. 1 17. The transverse electrodisplacive actuator array of claim 1 in which said actuator elements are single crystal materials. 2 1 18. The transverse electrodisplacive actuator array of claim 1 in which said

2 reflective surface is a continuous surface.

XIN-102j JSI:dmg